Amendments to the Specification:

Please replace the title as follows:

RECTIFYING DEVICE AND ELECTRONIC CIRCUIT EMPLOYING SAME, AND

PROCESS FOR PRODUCING RECTIFYING DEVICE

RECTIFYING DEVICE, ELECTRONIC CIRCUIT USING THE SAME, AND METHOD

OF MANUFACTURING RECTIFYING DEVICE

Please replace the paragraph beginning on page 123, line 5, with the following rewritten paragraph:

An aluminum electrode 3 serving as a main electrode was formed in advance on a silicon wafer (not shown)(available from Advantech Co., Ltd, 76.2 mmΦ (diameter of 3 inches), thickness of 380 μm, thickness of a surface oxide film of 1 μm) serving as a substrate. An alumina (Al₂O₃) layer 4 for forming a barrier was laminated by means of deposition on the aluminum electrode 3.